

ABSTRACT

1 A semiconductor workpiece processing apparatus having a
2 first chamber, a transport vehicle, and another chamber.
3 The first chamber is capable of being isolated from an
4 outside atmosphere. The transport vehicle is located in
5 the first chamber and is movably supported from the first
6 chamber for moving linearly relative to the first
7 chamber. The transport vehicle includes a base, and an
8 integral semiconductor workpiece transfer arm movably
9 mounted to the base and capable of multi-access movement
10 relative to the base. The other chamber is communicably
11 connected to the first chamber via a closable opening of
12 the first chamber. The opening is sized to allow the
13 transport vehicle to transit between the first chamber
14 and the other chamber through the opening.